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- 1. A method of fabricating a microfluidic device, comprising:

 providing first and second substrate layers;

 fabricating a microscale groove into at least a first surface of at least one of the first and second layers, and concurrently fabricating an alignment structure into the at least one surface of the first or second layers at a desired position relative to the microscale groove;

 mating one or more of a third component of the microfluidic device and a tool with the alignment structure to align the third component or the tool relative to the microscale groove.
 - 2. The method of claim 1, wherein the first substrate comprises a silica-based substrate and the alignment structure is etched into the first surface of the first substrate.
 - 3. The method of claim 1, wherein the first substrate comprises a polymeric substrate and the alignment structure is embossed onto the first surface of the first substrate.
 - 4. The method of claim 1, wherein the first substrate comprises a polymeric substrate and the alignment structure is injection molded onto the first surface of the first substrate.
 - 5. The method of claim 1, wherein the alignment structure comprises a depression on the first surface, and the tool comprises a drill.
 - 6. The method of claim 1, wherein the third component comprises a capillary, and the alignment structure comprises an aperture or well that is configured to receive the capillary element.
- The method of claim 25, wherein the alignment structure comprises a notch at an edge of the first surface of the first substrate, the first groove terminating in the notch, the notch being sized to receive the capillary element and such that a capillary channel disposed through the capillary element is in fluid communication with the groove.

rectangular capillary having a capillary channel disposed therethrough.

The method of claim 12, wherein the capillary element comprises a

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